



MATERIALS SUBSTRATES

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NEYCO has a complete range of crystal substrates for a wide variety of applications, including Semiconductor, Biotechnology, Nanotechnology, and MEMS. NEYCO is your one stop source for advanced materials for both R&D laboratory use and industry production. We can help you to locate, specify, and purchase unique materials in an efficient and cost effective manner.



STANDARD SUBSTRATE PARAMETERS

Substrates and wafers are manufactured by a technology, which is specially adapted to the respective material. Additionally we produce substrates and wafers customer-specific in all possible orientations, sizes and geometries and with smaller tolerance.

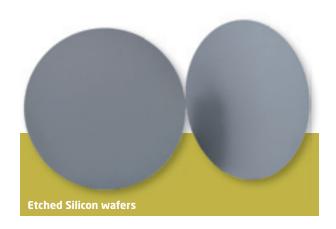
Orientations	(100), (111), (110) for cubic crystals (110), (001) for tetragonal crystals (0001), (1-102), (11-20), (10-10) for hexagonal crystals (110), (001) for orthorhombic crystals other orientations on request Standard: edges are oriented		
Tolerance of orientation	Maximum 30'; typical < 20' higher precision on request		
Standard sizes	10x10 mm, 10x5 mm, 12.7x12.7 mm, 15x15 mm, 20x20 mm, 25x25 mm, ø 1", ø 2", ø 3" other sizes on request		
Tolerance of sizes	+0/-0.05 mm		
Thickness	0.5 mm, 1.0 mm (standard) other thicknesses down to 0.1 mm on request		
Tolerance of thickness	+0.05/-0.05 mm		
Polish	One side, two sides optical polish of lateral sides (cylinders) on request		
Surface quality	Scratchfree at magnification of 50		
Roughness: (at λ _{Cutoff} = 0.08 mm)	Ra: typ. better than 0.5 nm Rq: typ. better than 1 .0 nm Rt: typ. better than 2.0 nm		
Parallelity	Typ. better than 10'		
Flatness	Max.1 μm/10 mm (test region 98% of the wafer area)		

Micro-roughness measured with Kugler Interferometermicroscope (lateral resolution: $0.64~\mu m$, vertical resolution (theoretically): 0.01~nm).

Silicon Wafers

MATERIALS CHARACTERISTICS

Silicon wafers are cut from silicon single crystal using internal diameter diamond discs. Silicon wafers are lapped of both sides with abrasive mixture. After cutting or lapping the wafers are washed in ultrasonic washers or undergo active washing. The wafers' edges are mechanically rounded. Silicon wafers are etched in acid mixture or alkaline. Wafers surface is alkaline or acid etched according to the customer's request. Active sides of the wafers (for single side polished wafers) or both sides (for two sides polished wafers) are chemo-mechanically polished.



APPLICATIONS

Wafers are used for production of silicon substrates and membranes.

The below mentioned parameters are dealing with our standard production. On the customer's request we are ready to discuss orders for wafers with some other parameters, for instance:



- Low radial resistivity variation (RRV) combined with the uniform distribution of dopants in the crystal (this parameter depends on shape of phase boundary and the phenomena in the boundary layer during monocrystalization process).
- Perfect crystallographic structure of material (free from swirls, with dislocations density lower than recommended by SEMI standard - 500/cm²).
- Low oxygen concentration (0, < 30 ppm).
- Tolerance of orientation better than 0.10°.
- Very good polished surface (one or both sides polished depending on technology and the type of products).



STANDARD SPECIFICATIONS

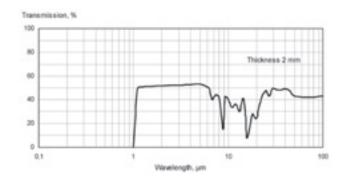
		CRYSTAL GRO	WTH			
Growth method		Czochralski (CZ) Floating zone (FZ)				
Orientation			<111>,	<100>		
Diameters			1" to 3	00 mm		
	CRYST	ALLOGRAPHIC I	PROPERTIES			
Crystal structure			Cubic a	= 0.543 nm		
Dopant available		N-t	P-type ype: Phosphorus,		enic	
	P	HYSICAL PROP	ERTIES			
Density			2.329	g.cm ⁻³		
Melting point			141	.7°C		
Hardness			7 M	lohs		
Thermal expansion			2.3.1	0 ⁻⁶ K ⁻¹		
Resistivity range			0.001 - 10) 000 Ω.cm		
Band gap (at 273 K)			1.10	6 eV		
Thermal conductivity		147 W.m ⁻¹ .K ⁻¹				
Carrier mobility			μ _e = 1350 μ _h = 480 α	cm ² .V ⁻¹ .s ⁻¹ cm ² .V ⁻¹ .s ⁻¹		
Conductivity type			P-type o	r N-type		
	С	HEMICAL PROP	ERTIES			
Solubility in water			0.005 g	/100 cm³		
Solubility in acids	Soluble					
Solubility in organic solvents	Insoluble					
	(OPTICAL PROPE				
Absorption coefficient			0.01 cm	¹ at 5 µm		
Transmission range (thickness 2 mm)	1.2 - 15.0 μm					
Refractive index n	3.0 µm	5.0 µm	6.0 µm	7.0 µm	8.0 µm	10.0 µm
Reflactive fluex fi	3.432	3.422	3.420	3.419	3.418	3.417

TECHNICAL DATA: AS CUT, LAPPED, ETCHED, POLISHED

Diameter (mm)	50.8 ± 0.3	76.0 ± 0.5	100 ± 0.5	125 ± 0.5	150 ± 0.5
Orientation	<100>	<100>	<100>	<100>	<100>
Thickness (µm)	40 to 25000	60 to 25000	70 to 25000	100 to 5000	150 to 5000
Thickness tolerance (µm) Standard Typical	± 25 ± 10	± 25 ± 10	± 25 ± 15	± 25 ± 20	± 25 ± 20
Total thickness variation TTV max	10	15	15	20	25

Diameter (mm)	50.8 ± 0.3	76.0 ± 0.5	100 ± 0.5	125 ± 0.5	150 ± 0.5
Orientation	<111>	<111>	<111>	<111>	<111>
Thickness (µm)	100 to 25000	150 to 25000	200 to 25000	250 to 5000	350 to 5000
Thickness tolerance (µm) Standard Typical	± 25 ± 10	± 25 ± 10	± 25 ± 15	± 25 ± 20	± 25 ± 25
Total thickness variation TTV max	10	15	15	20	25

TRANSMISSION SPECTRUM (high resistivity Si)



RECOMMENDED APPLICATIONS

Wafer Resistivity (ohm.cm)	< 0.05	1-5	6 - 12	> 30
Application	Epitaxial substrate	Solar cell	IC, OE devices or sensors	Special device or component

THERMAL OXIDATION

On request, a thermal oxidation can be grown on our Silicon wafers.

- Oxidation thickness: 100 nm to max. 2 μm.
- Wafer sizes: up to 4".

OTHER SERVICE

We can made special vacuum coatings on wafers: for example, we can deposit a precoating of Chromium or Titanium before a thin film of Gold, or any other evaporated or sputtered material. Contact us for your specific needs.



Single Crystal Substrates

Sapphire Al ₂ O ₃ substrate	J 08	Magnesium Aluminum Oxide MgAl ₂ O ₄ substrate	J 27
Barium Fluoride BaF ₂ substrate	J 09	Magnesium Fluoride MgF ₂ substrate	J 28
Barium Titanate BaTiO ₃ substrate	. J 10	Magnesium Oxide MgO substrate	J 29
Calcium Fluoride CaF ₂ substrate	J 11	Manganese Oxide MnO substrate	J 30
Calcium Neodymium Aluminate		Sodium Chloride NaCl substrate	J 31
CaNdAlO ₄ (CNAO) substrate	J 12	Neodymium Gallate NdGaO ₃ (NGO) substrate	J 32
Cadmium Sulfide CdS substrate	. J 13	Nickel Oxide NiO substrate	J 32
Cadmium Selenide CdSe substrate	. J 13	Quartz SiO ₂ substrate	.] 33
Cadmium Telluride CdTe substrate Cobalt Oxide CoO substrate		Strontium Lanthanum Aluminate SrLaAlO ₄ substrate	J 34
Chromium Oxide Cr ₂ O ₃ substrate		Strontium Lanthanum Gallate SrLaGa ₃ O ₇ substrate	
Gallium Arsenide GaAs substrate	J 16	Strontium Lanthanum Gallate	•
Gallium Phosphide GaP substrate	J 17	SrLaGaO ₄ substrate	J 35
Gadolinium Gallium Garnet Gd ₃ Ga ₅ O ₁₂		Strontium Titanate SrTiO ₃ substrate	.] 36
(GGG) substrate	J 18	Titanium Oxide (Rutile) TiO ₂ substrate	J 37
Germanium Ge substrate	J 19	Yttrium Aluminium Garnet Y ₃ Al ₅ O ₁₂	
Indium Arsenide InAs substrate	.] 20	(YAG) substrate	
Indium Phosphide InP substrate	J 21	Yttrium Aluminate YAIO ₃ (YAP) substrate	
Lantanum Aluminate LaAlO ₃ substrate	. J 22	Yttria Stabilized Zirconia (YSZ) substrate	
Lithium Aluminate LiAlO ₂ substrate	. J 23	Zinc Oxide ZnO substrate	
Lithium Fluoride LiF substrate	. J 23	Zinc Sulfide ZnS substrate	_
Lithium Gallate LiGaO ₂ substrate	J 25	Zinc Selenide ZnSe substrate	
Lithium Niobate LiNbO ₃ substrate		Zinc Telluride ZnTe substrate	J 45
Lithium-Strontium-Aluminum-Tantalum-Oxide (LSAT) substrate	126		

SAPPHIRE Al₂O₃ SUBSTRATE

Sapphire (single crystal of Al_2O_3) is being used extensively as a substrate for III-V nitrides and for many other epitaxial films. Single crystal sapphire wafer plays an increasingly important role as a material for blue LED, high Tc superconductor and microwave applications, due to its high strength, high anti-corrosion, high anti-abrasion, low dielectric loss and good electrical insulation.

NEYCO provides sapphire substrates with complete orientation options including C plane, A plane, R plane and M plane, in diameter range from 1" to 4", square substrate is also available as well, size from 10 x 10 mm to 100 x 100 mm. NEYCO can offer EPI ready grade sapphire wafer for your epitaxial growth.

FEATURES

- High working temperature
- Good thermal conductivity
- Superior mechanical properties
- High anti corrosion
- Stable dielectric constant & low dielectric loss
- Excellent light transmission

APPLICATIONS

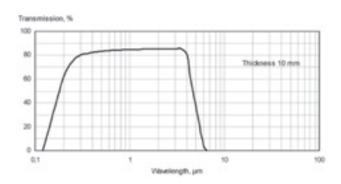
- Blue LED substrate
- Superconductor substrate
- Electronics and optoelectronics
- UV and IR optics

	CRYSTAL GROWTH				
Growth method	Czochralski (CZ)				
Maximum size	Ø 4"				
	CRYSTALLOGRAPHIC PROPERTIES				
Crystal structure	Hexagonal a = 0.477 nm c = 1.304 nm				
Color	Colourless				
	PHYSICAL PROPERTIES				
Density	3.98 g.cm ⁻³				
Melting point	2052°C				
Hardness	9 Mohs				
Thermal expansion	Vertical c-axis: 6.2.10 ⁻⁶ K ⁻¹ Parallel c-axis: 5.4.10 ⁻⁶ K ⁻¹				
Thermal conductivity	Vertical c-axis: 23.1 W.m ⁻¹ .K ⁻¹ Parallel c-axis: 25.2 W.m ⁻¹ .K ⁻¹				
Heat capacity	761 J.kg ⁻¹ .K ⁻¹				
Dielectric constant	Vertical c-axis: 9.4 Parallel c-axis: 11.5				
Loss Tangent at 10 GHz	Vertical c-axis: 8.6.10 ⁻⁸ Parallel c-axis: 3.10 ⁻⁸				
	CHEMICAL PROPERTIES				
Solubility in water	98.10 ⁻⁶ g/100 cm ³				
Solubility in acids	Insoluble				
Solubility in organic solvents	Not declarate				



OPTICAL PROPERTIES					
Absorption coefficient	0.2 cm ⁻¹ at 0.2 μm 0.02 cm ⁻¹ at 0.4 μm 0.46 cm ⁻¹ at 5 μm				
Transmission range (thickness 10 mm)	0.17 - 5.0 μm				
Refractive index n	1 μm	2 μm	3 µm	4 μm	
Refractive fildex fi	1.7545	1.7374	1.7015	1.6748	

TRANSMISSION SPECTRUM



BARIUM FLUORIDE BaF₂ SUBSTRATE

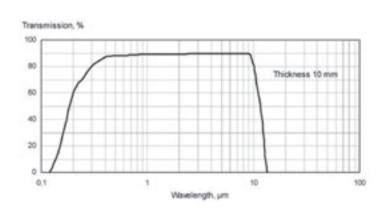
APPLICATIONS

IR and UV window, prism, substrate.

	CRYSTAL GROWTH					
Growth method	Stockbarger technique					
Maximum size	Ø 150 mm					
	CRYSTALLOGRAPHIC PROPERTIES					
Crystal structure	Cubic a = 0.6196 nm					
Cleavage plane	<111>					
	PHYSICAL PROPERTIES					
Density	4.83 g.cm ⁻³					
Melting point	1354℃					
	PHYSICAL PROPERTIES					
Hardness	3 Mohs					
Thermal expansion	16.5 - 19.2 x 10 ⁻⁶ K ⁻¹					

PHYSICAL PROPERTIES						
Thermal conductivity			7.1 W	.m ⁻¹ .K ⁻¹		
Specific heat capacity			456 J.	.kg ⁻¹ .K ⁻¹		
	C	HEMICAL PROP	ERTIES			
Solubility in water			0.17 g/	′100 cm³		
Solubility in acids		Soluble				
Solubility in organic solvents		Not declarate				
OPTICAL PROPERTIES						
Absorption coefficient	0.20 cm ⁻¹ at 0.2 μm 0.08 cm ⁻¹ at 0.4 μm 0.13 cm ⁻¹ at 10.6 μm					
Refractive index n	0.2 µm	0.5 µm	1.0 µm	5.0 µm	10.0 μm	12.0 µm
	1.5573	1.4779	1.4686	1.4511	1.4014	1.3696

TRANSMISSION SPECTRUM



BARIUM TITANATE BaTiO₃ SUBSTRATE

	CRYSTAL GROWTH				
Growth method	Czochralski (CZ)				
Maximum size	10 x 10 mm				
	CRYSTALLOGRAPHIC PROPERTIES				
Crystal structure	Tetragonal a = 0.3992 nm c = 0.4036 nm				
	PHYSICAL PROPERTIES				
Density	8.82 g.cm ⁻³				
Melting point	1600°C				
Hardness	5 Mohs				



CALCIUM FLUORIDE CaF₂ SUBSTRATE

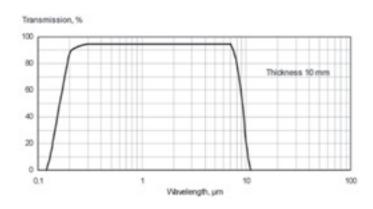
APPLICATIONS

IR windows and lens, prism.

STANDARD SPECIFICATIONS

		CRYSTAL GRO	√TH			
Growth method	Stockbarger technique					
Maximum size			Ø 20	0 mm		
	CRYS1	ALLOGRAPHIC F	PROPERTIES			
Crystal structure			Cubic a =	0.5462 nm		
Cleavage plane			<11	L1>		
	F	HYSICAL PROP	ERTIES			
Density			3.18	g.cm ⁻³		
Melting point			141	.8°C		
Hardness			4 M	ohs		
Thermal expansion	16.2 - 19.4 x 10 ⁻⁶ K ⁻¹					
Thermal conductivity	9.17 W.m ⁻¹ .K ⁻¹					
Specific heat capacity	888 J.kg ⁻¹ .K ⁻¹					
	C	HEMICAL PROP	RTIES			
Solubility in water	0.0016 g/ 100 cm³					
Solubility in acids			Uness	sential		
Solubility in organic solvents			Insoluble	in acetone		
	(OPTICAL PROPE	RTIES			
Transmission range (Thickness 10 mm)	0.15 - 9.0 μm					
	OPTICAL PROPERTIES					
Refractive index	0.2 µm	0.5 µm	1.0 µm	5.0 µm	10.0 µm	12.0 µm
Reflactive fluex	1.4951	1.4365	1.4289	1.3990	1.3002	1.2299
Absorption coefficient	0.10 cm ⁻¹ at 0.2 μm 0.01 cm ⁻¹ at 0.4 μm 0.03 cm ⁻¹ at 2.6-2.9 μm					

TRANSMISSION SPECTRUM



CALCIUM NEODYMIUM ALUMINATE CaNdAIO₄ (CNAO) SUBSTRATE

MATERIAL CHARACTERISTICS

High quality YBaCuo, BiSrCaCuO, Bi(Pb)CaCuO and TlBaCaCuO thin films have been grown on ${\rm CaNdAlO_4}$ substrates by different techniques.

CRYSTAL GROWTH							
Growth method	Czochralski (CZ)						
Maximum size	Ø 18 - 20 mm						
Standard thickness	0.5 to 1 mm						
	CRYSTALLOGRAPHIC PROPERTIES						
Crystal structure	Tetragonal $a = 0.369 \text{ nm}$ $c = 2.215 \text{ nm}$						
Color	Violet						
Twin structure	No						
	PHYSICAL PROPERTIES						
Density	5.527 g.cm ⁻³						
Melting point	1860°C						
Thermal expansion	Along a-axis: 8.67.10 ⁻⁶ K ⁻¹ Along c-axis: 1.57.10 ⁻⁵ K ⁻¹						
Dielectric constant	20						
Loss tangent (at 10 GHz)	2.10 ⁻³						
	OPTICAL PROPERTIES						
Transmission range	220 to 6670 nm (excluding Nd range)						
Refractive index n	1.941						



CADMIUM SULFIDE CdS SUBSTRATE

STANDARD SPECIFICATIONS

CRYSTAL GROWTH					
Growth method	Seeded vapour phase growth				
Maximum size	Ø 50 mm				
	CRYSTALLOGRAPHIC PROPERTIES				
Crystal structure	Hexagonal a = 0.4135 nm c = 0.6749 nm				
	PHYSICAL PROPERTIES				
Density	4.82 g.cm ⁻³				
Melting point	1475°C				
Hardness	4 Mohs				
Thermal expansion	4.2.10 ⁻⁶ K ⁻¹				
Resistivity range	> $10^8~\Omega$.cm (high resistivity) < $10^1~\Omega$.cm (low resistivity)				
Band gap at 300 K	2.53 eV				
Thermal conductivity	15.9 W.m ⁻¹ .K ⁻¹				
Conductivity type	N-type				
Carrier concentration	10 ⁹ - 10 ¹⁸ cm ⁻³				
Dielectric constant	Vertical c-axis: 8.28 Parallel c-axis: 8.64				

CADMIUM SELENIDE CdSe SUBSTRATE

	CDVCTAL CDOLUTIL						
CRYSTAL GROWTH							
Growth method	Seeded vapour phase growth						
Maximum size	Ø 50 mm						
	CRYSTALLOGRAPHIC PROPERTIES						
Crystal structure	Hexagonal a = 0.431 nm c = 0.7021nm						
	PHYSICAL PROPERTIES						
Density	5.816 g.cm ⁻³						
Melting point	1268°C						
Hardness	4 Mohs						
Thermal expansion	2.9.10 ⁻⁶ K ⁻¹						
Resistivity range	> $10^7~\Omega$.cm (high resistivity) < $10^1~\Omega$.cm (low resistivity)						
Thermal conductivity	3.49 W.m ⁻¹ .K ⁻¹						
Band gap at 300 K	1.74 eV						
Conductivity type	N-type						

CADMIUM TELLURIDE CdTe SUBSTRATE

		CRYSTAL GRO	WTH				
Growth method		Modified Bridgman (with Cd-reservoir)					
Maximum size			Ø 60	mm			
CRYSTALLOGRAPHIC PROPERTIES							
Crystal structure			Cubic a =	0.6481 nm			
Cleavage			<11	LO>			
	PI	HYSICAL PROP	ERTIES				
Density			5.855	g.cm ⁻³			
Melting point			109	12°C			
Hardness			3 M	ohs			
Thermal expansion			5.7.10	O-6 K-1			
Thermal conductivity		6.28 W.m ⁻¹ .K ⁻¹					
Resistivity range		> 10°Ω.cm					
Band gap at 300 K		1.5 eV					
Conductivity type		N-type, P-type					
	Cŀ	IEMICAL PROP	ERTIES				
Solubility in water		Insoluble					
Solubility in acids		Insoluble					
Solubility in organic solvents		Insoluble					
	0	PTICAL PROPE	RTIES				
Absorption coefficient	0.001 cm ⁻¹ at 10.6 μm						
Transmission range (thickness 2 mm)		0.9 μm to 24 μm					
Refractive index n	1 μm	5 μm	10 µm	15 µm	20 µm	30 µm	
Retractive index n	2.831	2.692	2.679	2.659	2.632	2.559	



COBALT OXIDE COO SUBSTRATE

STANDARD SPECIFICATIONS

	CRYSTAL GROWTH						
Growth method	Verneuil						
Maximum size	Ø 15mm						
	CRYSTALLOGRAPHIC PROPERTIES						
Crystal structure	Cubic a = 0.4267 nm						
Color	Black						
	PHYSICAL PROPERTIES						
Density	6.4 g.cm³						
Melting point	1935℃						
Hardness (Knoop test)	310 to 345						

CHROMIUM OXIDE Cr₂O₃ SUBSTRATE

CRYSTAL GROWTH							
Coor with one with a d							
Growth method	Verneuil						
Maximum size	Ø 15 mm						
	CRYSTALLOGRAPHIC PROPERTIES						
Crystal structure	Hexagonal a = 0.496 nm c = 1.3599 nm						
Color	Black						
	PHYSICAL PROPERTIES						
Density	5.2 g.cm ⁻³						
Melting point	2275℃						

GALLIUM ARSENIDE GAAS SUBSTRATE

Gallium Arsenide used for lenses and beam splitters provides an alternative to ZnSe in medium and high power CW CO2 laser systems. It is most useful in applications where toughness and durability are important. Its hardness and strength make it a good choice where dust or

abrasive particles tend to build up on or bombard the optical surfaces. When frequent cleaning by wiping is required, GaAs is excellent. The material is nonhygroscopic, safe to use in laboratory and field conditions and is chemically stable except when in contact with strong acids.

FEATURES

- High mobility
- High frequency
- Low power consumption

APPLICATIONS

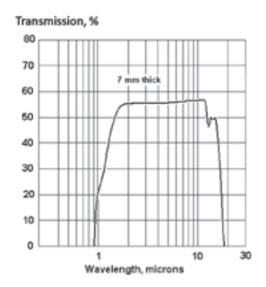
- Visible and infrared LED
- Light emitting diodes
- Laser diodes

CRYSTAL GROWTH										
Growth method		Czochralski (CZ) or Vertical Gradient Freeze								
Maximum size					Ø	4"				
Standard thickness					350 - 6	525 µm				
	C	RYSTALI	.OGRAPH	IIC PROF	PERTIES					
Crystal structure				(Cubic a	= 0.565 r	ım			
Dopant available				Silicor	, Tellurium	n, Zinc, Chi	romium			
		PHY	SICAL PE	ROPERTI	ES					
Density					5.32	g.cm ⁻³				
Melting point					123	38°C				
Hardness (Knoop test)					7.	50				
Thermal expansion	5.8.10 ⁻⁶ K ⁻¹									
Dielectric constant	12.85									
Band gap	1.42 eV									
Thermal conductivity	0.55 W.cm ⁻¹ .K ⁻¹									
Specific heat capacity	0.327 J.g ⁻¹ .K ⁻¹									
Conductivity				Semi-c	onducting	or semi-in	sulating			
Conductivity type	P-type or N-type									
	OPTICAL PROPERTIES									
Absorption coefficient	< 0.02 cm ⁻¹ at 10.6 μm									
Transmission range (thickness 7 µm)	1.0 to 22 μm									
Solubility in water	None									
Refractive index n	8 µm	10 µm	11 µm	13 µm	13.7 µm	14.5 µm	15 µm	17 µm	19 µm	21.9 µm
Rendelive index ii	3.34	3.13	3.04	2.97	2.89	2.82	2.73	2.59	2.41	2.12



Parameters	Undoped GaAs	Si Doped GaAs	Zn Doped GaAs	Cr Doped GaAs	Te Doped GaAs
Doping	Undoped	Si	Zn	Cr	Te
Conductor type	N, (SI)	N	Р	SI	N
Carrier concentration (cm ⁻³)	-	(5 - 15).10 ¹⁷	> 5.10 ¹⁸	-	5 - 20.10 ¹⁷
Resistivity (Ω.cm)	> 1.10 ⁻⁷	-	-	> 5.10 ⁷	-
Mobility (cm².V ⁻¹ .s ⁻¹)	> 4500	3000 - 1800	> 50	> 3000	> 1500
E.P.D. (cm ⁻²)	< 5.10 ⁴	1.10 ⁴ - 3.10 ³	< 5.10 ⁴	> 8.104	< 3000

TRANSMISSION SPECTRUM



GALLIUM PHOSPHIDE GaP SUBSTRATE

GaP single crystals are grown by the Czochralski technique and are widely used for red, yellow and green LED substrates. NEYCO provides high quality as-cut GaP

wafers for LPE in mass production, and also supplies EPI polished wafers for CVD and MBE applications.

	CRYSTAL GROWTH						
Growth method	Czochralski (CZ)						
Maximum size	Ø 2"						
Standard thickness	500 μm						
	CRYSTALLOGRAPHIC PROPERTIES						
Crystal structure	Cubic a = 0.545 nm						
	PHYSICAL PROPERTIES						
Conductivity	Semi-conducting (SI)						
Conductivity type	N-type						
Dopant available	Silicon						

Dopant	Si doped	Undoped				
Carrier concentration	2 - 8.10 ¹⁷ cm ⁻³	4 - 6.10 ¹⁶ cm ⁻³				
EPD	< 3.10 ⁵ cm ⁻²	< 3.10 ⁵ cm ⁻²				
Resistivity range	~ 0.03 Ω.cm	~ 0.3 Ω.cm				
Density	4.13 g.cm ⁻³					
Melting point	1480°C					
Thermal expansion	5.3.10 ⁻⁶ K ⁻¹					
Band gap	2.26 eV					
Thermal conductivity	1.1 W.cm ⁻¹ .l	K ⁻¹ at 300 K				

GADOLINIUM GALLIUM GARNET Gd₃Ga₅O₁₂ (GGG) SUBSTRATE

	CRYSTAL GROWTH				
Growth method	Czochralski (CZ)				
Maximum size	Ø 3"				
	CRYSTALLOGRAPHIC PROPERTIES				
Crystal structure	Cubic a = 1.2382 nm				
Color	Pale yellow				
	PHYSICAL PROPERTIES				
Density	7.02 g.cm ⁻³				
Melting point	1730°C				
Thermal expansion	9.7.10 ⁻⁶ K ⁻¹				



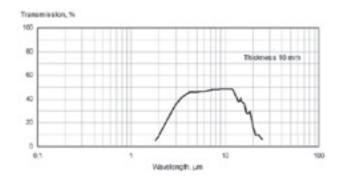
GERMANIUM GE SUBSTRATE

APPLICATIONS

- IR optics
- Solar cell application
- Optical fiber production
- Semiconductor and electronics device

		CRYSTAL GROU	√TH			
Growth method	Czochralski (CZ)					
Maximum size	Ø 3"					
	CRYSTALLOGRAPHIC PROPERTIES					
Crystal structure			Cubic a	= 0.565 nm		
Dopant available			Antimony (N), Gallium (P)		
Cleavage			<11	L1>		
	Р	HYSICAL PROP	ERTIES			
Density			5.32 {	g.cm ⁻³		
Melting point			937	7°C		
Hardness			6 M	ohs		
Thermal expansion			5.75.1	.0 ⁻⁶ K ⁻¹		
	Р	HYSICAL PROP	ERTIES			
Resistivity range	N-type: < 0.4 Ω.cm P-type: 0.005 - 30 Ω.cm Undoped: > 30 Ω.cm					
Specificity heat capacity	310 J.kg ⁻¹ .K ⁻¹					
Band gap at 273 K	0.67 eV					
Thermal conductivity	58.6 W.m ⁻¹ .K ⁻¹					
Carrier mobility	$\mu_{\rm e}$ = 3900 cm ² .V ⁻¹ .s ⁻¹ $\mu_{\rm h}$ = 1900 cm ² .V ⁻¹ .s ⁻¹					
Conductivity type	P-type or N-type					
	CHEMICAL PROPERTIES					
Solubility in water	Insoluble					
Solubility in acids	Soluble in mixture of HCI and HNO ₃ and H ₂ O ₂					
Solubility in organic solvents	Insoluble					
	(OPTICAL PROPE	RTIES			
Absorption coefficient	0.02 cm ⁻¹ at 10.6 μm					
Transmission range (thickness 10 mm)	2 to 18 µm					
Refractive index n	2.0 µm	5.0 µm	8.0 µm	10.0 µm	11.0 µm	15.0 µm
Reflactive fildex fi	4.1079	4.0153	4.0053	4.0040	4.0031	4.0017

TRANSMISSION SPECTRUM



INDIUM ARSENIDE INAS SUBSTRATE

NEYCO provides InAs wafers (Indium Arsenide) to optoelectronics in diameter up to 2 inch. InAs crystal has high uniformity of electrical parameters and low defect density, suitable for MBE or MOCVD epitaxial growth.

	CRYSTAL GROWTH					
Growth method	Czochralski (CZ)					
Maximum size	Ø 2"					
Standard thickness	500 μm					
	CRYSTALLOGRAPHIC PROPERTIES					
Crystal structure	Cubic					
	PHYSICAL PROPERTIES					
Band gap	0.4 eV					
Conductivity	Semi-conducting (SI)					
Conductivity type	P-type or N-type					
Dopant available	Silicon, Zinc					

DOPANT AVAILABLE	TYPE	CARRIER CONCENTRATION (cm³)	MOBILITY (cm².V¹.s¹)
Undoped	N	-	> 20000
Si	N	1.10 ¹⁷ - 3.10 ¹⁸ cm ⁻³	10000 - 25000
Zn	Р	1.10 ¹⁷ - 5.10 ¹⁸ cm ⁻³	100 - 500



INDIUM PHOSPHIDE INP SUBSTRATE

NEYCO supplies high quality InP single crystal substrates for semiconductor industries. The wafers are cut along precise orientation and highly EPI polished.

APPLICATIONS

InP has been a focus of development since the early 1980s, and today the material is being used as a platform for a wide variety of fiber communications components, including lasers, LEDs, semiconductor optical amplifiers, modulators and photo-detectors.

InP applications for discrete active devices are widespread in communications networking, making it the natural starting place for wholesale integration of passive devices for a complete system on a chip. As a semiconductor material, InP can provide all-in-one integrated functionality that includes light generation, detection, amplification, high-speed modulation and switching, as well as passive splitting, combining and routing. The same material can be used to make high-speed modulators, switches, amplifiers and detectors, or just passive wave guides for interconnecting these diverse devices.

	CRYSTAL GROWTH			
Growth method	Czochralski (CZ)			
Standard thickness	500 μm			
Maximum size	Ø 2"			
	CRYSTALLOGRAPHIC PROPERTIES			
Crystal structure	Face-centered cubic (Zinc blende)			
PHYSICAL PROPERTIES				
Band gap	1.344 eV			
Conductivity	Semi-conducting or semi-insulating (SI)			
Conductivity type	P-type or N-type			
Dopant available	Silicon, Tin, Zinc, Iron			
Density	4.81 g.cm ⁻³			
Melting point	1082°C			
Thermal conductivity	0.68 W.cm ⁻¹ .K ⁻¹ at 300 K			

DOPANT AVAILABLE	TYPE	CARRIER CONCENTRATION (cm ⁻³)	MOBILITY (cm² .V¹.s¹)	RESISTIVITY (Ω.cm)	EPD (cm²)
Undoped	N	0.8 - 2.0 .1015	3600 - 4000	0.03 - 0.2	5-6.104
En Ci	Sn, Si N	0.5 - 1.0 .1018	200 - 2400	0.001 - 0.002	3-5.10 ⁴
311, 31		0.5 - 1.0 .10 ¹⁸	1500 - 2000	0.0025 - 0.007	2-2:10.
Zn	Р	0.8 - 2.0 .1018	2500 - 3500	0.0025 - 0.006	1-3.104
۷11	۲	2.5 - 4.0 .10 ¹⁸	1300 - 1600	0.0023 - 0.006	1-2.10
Fe	SI	0.1 - 1.0	2000	10 ⁷ - 10 ⁸	4-5.10 ⁴

LANTANUM ALUMINATE LaAIO₃ SUBSTRATE

LaAlO₃ single crystal provides a good lattice match to many materials with perovskite structure. It is an excellent substrate for epitaxial growth of high Tc superconductors,

magnetic and ferro-electric thin films. The dielectric properties of $LaAlO_3$ crystal are well suitable for low loss microwave and dielectric resonance applications.

CRYSTAL GROWTH				
Growth method	Czochralski (CZ)			
Max. size	Ø 3"			
Standard thickness	0.5 to 1 mm			
	CRYSTALLOGRAPHIC PROPERTIES			
Crystal structure	Rhombohedral at 25°C a = 0.5357 nm			
	Cubic at > 435°C a = 0.379 nm			
Twin structure	Twins // to the <100>-planes of the pseudocubic cell			
Color	Tan to brown based on annealing condition			
PHYSICAL PROPERTIES				
Density	6.52 g.cm ⁻³			
Melting point	2180°C			
Thermal expansion	9.2.10 ⁻⁶ K ⁻¹			
Dielectric constant	24.5			
Loss tangent (at 10 GHz)	~ 3.10⁴ at 300 K ~ 6.10⁵ at 77 K			
	CHEMICAL PROPERTIES			
Chemical stability	Insoluble in mineral acids at 25°C and soluble in H₃PO₃ at > 150°C			



LITHIUM ALUMINATE LIAIO₂ SUBSTRATE

 ${\rm LiAIO_2}$ is a potential substrate for III-V nitride thin films due to its excellent lattice mismatch to GaN (<0.2% at <100>), chemical stability at high temperature and cost effective.

STANDARD SPECIFICATIONS

CRYSTAL GROWTH					
Growth method	Czochralski (CZ)				
Maximum size	Ø 2"				
	CRYSTALLOGRAPHIC PROPERTIES				
Crystal structure	Tetragonal a = 0.517 nm c = 0.626 nm				
Color	Transparent				
	PHYSICAL PROPERTIES				
Density	2.2 g.cm ⁻³				
Melting point	1900°C				
Hardness	7.5 Mohs				

LITHIUM FLUORIDE LIF SUBSTRATE

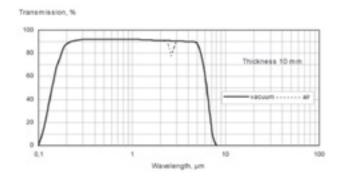
APPLICATION

UV window and prism, without deliquescence.

	CRYSTAL GROWTH					
Growth method	Stockbarger technique					
Maximum size	Ø 150 mm					
	CRYSTALLOGRAPHIC PROPERTIES					
Crystal structure	Cubic a = 0.4026 nm					
Cleavage plane	<100>					
	PHYSICAL PROPERTIES					
Density	2.60 g.cm ⁻³					
Melting point	870°C					

PHYSICAL PROPERTIES						
Hardness	4 Mohs					
Thermal expansion			28.1 - 34	.8.10 ⁻⁶ K ⁻¹		
Thermal conductivity			14.2 W	<i>I</i> .m ⁻¹ .K ⁻¹		
Specific heat capacity			1562 J	.kg ⁻¹ .K ⁻¹		
	C	HEMICAL PROP	ERTIES			
Solubility in water			0.27 g/	100 cm³		
Solubility in acids		Soluble				
Solubility in organic solvents	Insoluble in acetone and ethylalcohol					
OPTICAL PROPERTIES						
Absorption coefficient	0.05 cm ⁻¹ at 0.2 μm 0.02 cm ⁻¹ at 0.4 μm 0.03 cm ⁻¹ at 2.6-2.9 μm					
Transmission range (thickness 10 mm)	0.12 - 6.5 μm					
Refractive index n	0.2 µm	0.5 µm	1.0 µm	3.0 µm	5.0 µm	6.0 µm
Renactive Index n	1.4390	1.3943	1.3871	1.3666	1.3266	1.2975

TRANSMISSION SPECTRUM





LITHIUM GALLATE LIGaO₂ SUBSTRATE

 $LiGaO_2$ single crystal was grown in 1960's for laser application. However, it is found out that $LiGaO_2$ is a potential substrate for III-V nitride thin films due to its excellent lattice mismatch to GaN (<0.2%), chemical stability at high temperature and cost effective.

STANDARD SPECIFICATIONS

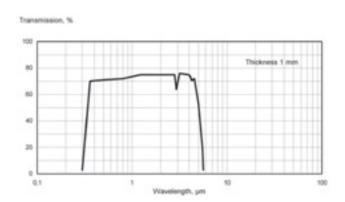
CRYSTAL GROWTH					
Growth method	Czochralski (CZ)				
Maximum size	Ø 20 mm				
	CRYSTALLOGRAPHIC PROPERTIES				
Crystal structure	Orthorhombic $a = 0.54 \text{ nm}$ $b = 0.6379 \text{ nm}$ $c = 0.5012 \text{ nm}$				
Color	White to brown				
Twin structure	No twins and inclusion				
	PHYSICAL PROPERTIES				
Density	4.18 g.cm ⁻³				
Melting Point	1600°C				

LITHIUM NIOBATE LINDO₃ SUBSTRATE

CRYSTAL GROWTH				
Growth method	Czochralski (CZ)			
	CRYSTALLOGRAPHIC PROPERTIES			
Crystal structure	Hexagonal a = 0.5148 nm c = 1.3863 nm			
PHYSICAL PROPERTIES				
Density	4.64 g.cm ⁻³			
Melting point	1250°C			
Hardness	5 Mohs			
Thermal expansion	Vertical c-axis: $15.4.10^{-6}~\text{K}^{-1}$ Parallel c-axis: $7.5.10^{-6}~\text{K}^{-1}$			

OPTICAL PROPERTIES				
Transmission range	0.4 - 2.90 μm			
Refractive index:	0.633 μm 1.064 μm 1.30 μm			
n _o	2.286	2.232	2.220	
n _e	2.203	2.156	2.146	

TRANSMISSION SPECTRUM



LANTHANUM-STRONTIUM-ALUMINUM-TANTALUM-OXIDE (LSAT) SUBSTRATE

LSAT $(LaAlO_3)_{0.3}$ $(Sr_2AlTaO_6)_{0.7}$ is a newly developing crystal with peroviskite structure and twin-free. LSAT has excellent lattice match with high Tc superconductors and many oxide materials. LSAT has lower melting point and can be grown by CZ technology at lower cost, therefore,

it is expected to replace $LaAlO_3$ and $SrTiO_3$ as a common single crystal substrate for epitaxial oxide thin films for gain magnetic ferro-electronic and superconductive devices.

CRYSTAL GROWTH			
Growth method	Czochralski (CZ)		
Maximum size	Ø 2"		
	CRYSTALLOGRAPHIC PROPERTIES		
Crystal structure	Cubic a = 0.7737 nm		
Twin structure	No twin and domain visible		
Color	Colorless to light brown based on annealing condition		
	PHYSICAL PROPERTIES		
Density	6.74 g.cm⁻³		
Melting point	1840°C		



PHYSICAL PROPERTIES		
Thermal expansion	10.10 ⁻⁶ K ⁻¹	
Dielectric constant	c constant ~ 22	
Loss tangent (at 8.8 GHz)	2.10 ⁻⁴ at 77 K	

MAGNESIUM ALUMINUM OXIDE MgAI₂O₄ SUBSTRATE

 ${\rm MgAl_2O_4}$ (spinel) single crystals are widely used for bulk acoustic wave and microwave devices and fast IC epitaxial substrates. It is also found that ${\rm MgAl_2O_4}$ is a good

substrate for III-V nitrides device. ${\rm MgAI_2O_4}$ crystal is very difficult to grow, due to the difficulty in maintaining a single phase structure.

CRYSTAL GROWTH			
Growth method	Czochralski (CZ)		
Maximum size	Ø 30 mm		
	CRYSTALLOGRAPHIC PROPERTIES		
Crystal structure	Cubic a = 0.8083 nm		
Color	Colourless		
PHYSICAL PROPERTIES			
Density	3.64 g.cm⁻³		
Melting Point	2130°C		
Hardness	8.0 Mohs		
Thermal expansion	7.10 ⁻⁶ K ⁻¹		

MAGNESIUM FLUORIDE MgF_2 SUBSTRATE

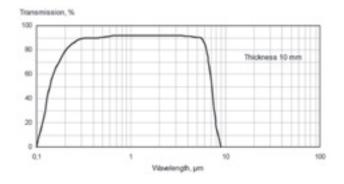
APPLICATIONS

VUV window and mirror, lens.

STANDARD SPECIFICATIONS

CRYSTAL GROWTH						
Growth method	Stockbarger technique					
Cleavage			<100>,	<110>		
Maximum size			Ø 90) mm		
	CRYST	ALLOGRAPHIC F	PROPERTIES			
Crystal structure				gonal c = 0.306 nm		
	P	PHYSICAL PROP	ERTIES			
Density			3.18	g.cm ⁻³		
Melting point			125	55°C		
Hardness			6 M	ohs		
Thermal expansion	Parallel c-axis: 10.86 - 14.54.10 ⁻⁶ K ⁻¹ Vertical c-axis: 6.23 - 9.25.10 ⁻⁶ K ⁻¹					
Specific heat capacity	920 J.kg ⁻¹ .K ⁻¹					
	CHEMICAL PROPERTIES					
Solubility in water	0.0076 g/100 cm ³					
Solubility in acids	Soluble					
Solubility in organic solvents	Insoluble in alcohol					
OPTICAL PROPERTIES						
Absorption coefficient (cm ⁻¹)	0.07 cm ⁻¹ at 0.2 μm 0.02 cm ⁻¹ at 5.0 μm					
Refractive index:	0.2 µm	0.5 µm	1.0 µm	3.0 µm	5.0 µm	7.0 µm
n _o	1.4231	1.3797	1.3736	1.3618	1.3400	1.3044
n _e	1.4367	1.3916	1.3852	1.3724	1.3487	1.3101

TRANSMISSION SPECTRUM





MAGNESIUM OXIDE MgO SUBSTRATE

MgO is an excellent single crystal substrate for thin films of ferro-magnetic, photo-electronic and high Tc superconductor materials.

FEATURES

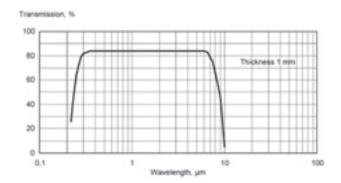
- Low dielectric loss
- Cleavage plane on the <100>

APPLICATIONS

- High Tc Superconductor
- Electronics and optoelectronics
- Microwave device

CRYSTAL GROWTH				
Growth method	Flux melt			
Standard thickness		0.5 to 1 mm		
Maximum size		Ø	2"	
	CRYSTALLOGR	APHIC PROPERTIES		
Crystal structure		Cubic a =	= 0.4216 nm	
Cleavage		<10	00>	
Twin structure		Withou	ıt twins	
Color		Colo	rless	
	PHYSICA	L PROPERTIES		
Density		3.58	g.cm ⁻³	
Melting point		2800°C		
Hardness	5.8 Mohs			
Thermal expansion	8.10 ⁻⁶ K ⁻¹			
Thermal conductivity	40.6 W.m ⁻¹ K ⁻¹			
Specific heat capacity	837 J.kg ⁻¹ .K ⁻¹			
Dielectric constant	8.1			
Loss tangent (at 10 GHz)	~ 9.10 ⁻³ at 77 K			
CHEMICAL PROPERTIES				
Chemical stability	Insoluble in mineral acids at 25 °C and soluble in $H_{3}PO_{3}$ at > 150 °C			
Solubility in water	0.00062 g/100 cm³			
	OPTICAL PROPERTIES			
Transmission range (thickness 1 mm)	0.3 - 7.0 μm			
Refractive index n	0.5 μm	1 µm	3 µm	5 μm
Relidetive illuex II	1.74	1.72	1.68	1.63

TRANSMISSION SPECTRUM



MANGANESE OXIDE MnO SUBSTRATE

	CRYSTAL GROWTH		
Growth method	Verneuil		
Maximum size	Ø 15 mm		
	CRYSTALLOGRAPHIC PROPERTIES		
Crystal structure	Cubic a = 0.4445 nm		
Color	Black		
	PHYSICAL PROPERTIES		
Density	5.4 g.cm³		
Melting point	1650°C		
Hardness (Knoop test)	300		



SODIUM CHLORIDE NaCI SUBSTRATE

Use only these crystals for fine research work requiring minimum 10 mm square uninterrupted areas.

- Formula: NaCl
- Appearance: Cubic clear (nearly transparent) crystals
- Density: 2.165 g.cm⁻³
- Solubility in water: a thin "wafer" that is 0.05" (1.27 mm) will dissolve in water at room temperature in roughly 30 seconds

GROW EPITAXIAL FILMS

These high quality research grade sodium chloride single crystal substrates offer a major advantage: the ability to grow epitaxial films on a featureless substrate.

The orientation of the film is related to the orientation of the substrate, producing areas of single crystal film. This feature is ideal for boundary diffusion studies and applications where a single crystal thin film is required. The film is easily removed by floating it off on water or by dissolving away the underlying substrate.

SIZES	PACKAGING	P/N
25 mm cubes	1	01817-AB
10 mm cubes	5	01807-AF
25 mm cubes	5	01817-AF

OFF-CUTS

- Use for class experiments and for the teaching of cleaving techniques
- Approximate size range: 20 mm to 45 mm
- Note: Some "fines" will be present as well

PACKAGING	P/N
100 g	01779-AB

NEODYMIUM GALLATE NdGAO₃ (NGO) SUBSTRATE

MATERIAL CHARACTERISTICS

- Excellent lattice matches to the typical HTSC composition
- Low dielectric constant and low dielectric loss tangent, which makes it attractive for microwave applications
- Good thermal properties
- No destructive phase transformations

STANDARD SPECIFICATIONS

CRYSTAL GROWTH			
Growth method	Czochralski (CZ)		
Maximum size	Ø 2"		
Standard thickness	0.5 to 1 mm		
	CRYSTALLOGRAPHIC PROPERTIES		
Crystal structure	Orthorhombic to $> 1000^{\circ}$ C a = 0.5426 nm b = 0.5496 nm c = 0.7707 nm Second order phase transformation at 950°C		
Twin structure	Without twins		
Color	Deep red to green		
PHYSICAL PROPERTIES			
Density	7.56 g.cm ⁻³		
Melting point	1750°C		
Hardness	5.9 Mohs		
Thermal expansion	11.10 ⁻⁶ K ⁻¹		
Dielectric constant (1 MHz)	20 at 300 K		

NICKEL OXIDE NIO SUBSTRATE

	CRYSTAL GROWTH			
Growth method	Verneuil			
Maximum size	Ø 15 mm			
	CRYSTALLOGRAPHIC PROPERTIES			
Crystal structure	Cubic a = 0.419 nm			
Color	Black			
PHYSICAL PROPERTIES				
Density	6.96 g.cm ⁻³			
Melting point	1998°C			
Hardness (Knoop test)	560 - 590			



QUARTZ SiO₂ SUBSTRATE

FEATURES

- High working temperature
- Good thermal conductivity
- · High stability
- High anti corrosion
- Superior mechanical properties
- Stable dielectric constant & low dielectric loss
- High optical transmission

APPLICATIONS

- Photo mask blank
- Sensors
- High frequency circuit (Microwave circuit)
- Biotech arrays
- Laser Optics
- Optical windows and lenses

CRYSTAL GROWTH		
Growth method	Hydrothermal synthesis	
Maximum size	100 x 100 mm	
Standard thickness	0.5 mm to 4 mm	
	CRYSTALLOGRAPHIC PROPERTIES	
Crystal structure	Hexagonal a = 0.490 nm c = 0.539 nm	
Color	Colourless	
PHYSICAL PROPERTIES		
Density	2.65 g.cm ⁻³	
Melting Point	1700°C	
Hardness	5.5 - 6.5 Mohs	
Thermal expansion	Vertical c-axis: 13.37.10 ⁻⁶ K ⁻¹ Parallel c-axis: 7.97.10 ⁻⁶ K ⁻¹	
Resistivity	$7.10^7\Omega$.cm	
Dielectric constant	3.7 - 3.9	

STRONTIUM LANTHANUM ALUMINATE SrLaALO₄ SUBSTRATE

SrLaAlO4 crystal is a promising substrate material for high Tc superconductor film and other oxide films. It has similar lattice constant to SrTiO₃, but better quality and lower cost because of CZ growth and lower melting point.

APPLICATIONS

High quality YBaCu, BiSrCaCuO, Bi(Pb)CaCuO and TlBaCaCuO thin films have been grown on $SrLaAlO_4$ substrates by different techniques.

STANDARD SPECIFICATIONS

CRYSTAL GROWTH						
Growth method	Czochralski (CZ)					
Maximum size	Ø 18 - 20 mm					
Standard thickness	0.5 to 1 mm					
CRYSTALLOGRAPHIC PROPERTIES						
Crystal structure	Tetragonal a = 0.3754 nm c = 1.2630 nm					
Twin structure	No					
Color	Light yellow					
	PHYSICAL PROPERTIES					
Density	5.924 g.cm ⁻³					
Melting point	1650℃					
Hardness	7 Mohs					
Thermal expansion	Along a-axis: 7.55.10 ⁻⁶ K ⁻¹ Along c-axis: 1.71.10 ⁻⁶ K ⁻¹					
Dielectric constant	17					
Thermal conductivity	At 12 K: 360 W.m ⁻¹ .K ⁻¹ At 300 K: 8.82 W.m ⁻¹ .K ⁻¹ At 450 K: 7.50 W.m ⁻¹ .K ⁻¹					
Dielectric loss tangent (at 10 GHz)	8.10 ⁻⁴ at 77 K					
OPTICAL PROPERTIES						
Transmission range	240 to 6670 nm					

STRONTIUM LANTHANUM GALLATE SrLaGA₃O₇ SUBSTRATE

CRYSTAL GROWTH				
Growth method	Czochralski (CZ)			
Maximum size	Ø 18 - 20 mm			
CRYSTALLOGRAPHIC PROPERTIES				
Crystal structure	Tetragonal a = 0.806 nm c = 0.534 nm			



CRYSTALLOGRAPHIC PROPERTIES				
Color	Orange			
PHYSICAL PROPERTIES				
Density	5.2 g.cm ⁻³			
Melting point	1760℃			
Dielectric constant	22			
Loss tangent (at 1 MHz)	5.7.10 ⁻⁵ at 300 K			

STRONTIUM LANTHANUM GALLATE SrLaGaO₄ SUBSTRATE

APPLICATIONS

High quality YBaCuO, BiSrCaCuO, Bi(Pb)CaCuO and TIBaCaCuO thin films have been grown on $SrLaGaO_4$ substrates by different techniques.

CRYSTAL GROWTH					
Growth method	Czochralski (CZ)				
Maximum size	Ø 18 - 20 mm				
Standard thickness	0.5 to 1 mm				
CRYSTALLOGRAPHIC PROPERTIES					
Crystal structure	Tetragonal a = 0.3843 nm c = 1.2680 nm				
Twin structure	No				
Color	Colorless to yellow				
	PHYSICAL PROPERTIES				
Density	6.389 g.cm ⁻³				
Melting point	1520°C				
Thermal expansion	Along a-axis: $10.1.10^6~{ m K}^1$ Along c-axis: $1890.10^5~{ m K}^1$				
Dielectric constant	22				
Loss tangent (at 10 GHz)	5.7.10 ⁻³ at 77 K				

STRONTIUM TITANATE STTIO3 SUBSTRATE

 ${\rm SrTiO_3}$ single crystal provides a good lattice match to most materials with Perovskite structure. It is an excellent substrate for epitaxial growth of HTS and many

oxide thin films. ${\rm SrTiO_3}$ single crystal has also been used widely for special optical windows and as high quality sputtering target.

STANDARD SPECIFICATIONS

CRYSTAL GROWTH					
Growth method	Verneuil				
Maximum size	Ø 2"				
CRYSTALLOGRAPHIC PROPERTIES					
Crystal structure	Cubic a = 0.3905 nm				
Twin structure	Without twins				
Color	Colorless to pale yellow				
PHYSICAL PROPERTIES					
Density	5.175 g.cm ⁻³				
Melting point	2080°C				
Hardness	6 Mohs				
Thermal expansion	9.10 ⁻⁶ K ⁻¹				
Dielectric constant	~ 300				
Loss Tangent (at 10 GHz)	2.10 ⁻² at 77 K				
CHEMICAL PROPERTIES					
Chemical stability	Insoluble in water				

Doped SrTiO₃ is used in the basic research and is applied as conducting material [e.g. back side contacting, application of certain surface sensitive measurements (STM)].

DOPANDS	Nb		ι	a
CONCENTRATION AT %	AVAILABLE	RESISTIVITY (Ω.cm)	AVAILABLE	RESISTIVITY (Ω.cm)
0.02	Χ	-	-	-
0.05	X	0.08	X	0.12
0.1	Х	0.03	X	-
0.2	X	-	-	-
0.5	Χ	0.005	X	0.006
1.0	Χ	0.003	X	-
2.0	X	-	-	-
5.0	-	-	X	0.0007



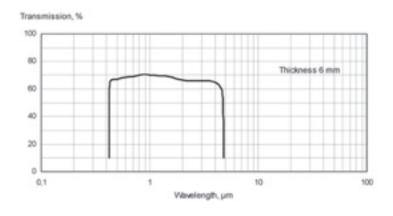
TITANIUM OXIDE (RUTILE) TiO₂ SUBSTRATE

Rutile (TiO₂) single crystal is one of the most suitable materials for spectral prisms and polarizing devices such as optical isolators and beam displacers because it has a

large birefringence with a high refractive index. Compared to YVO_4 , TiO_2 crystal is more stable chemically and physically.

STANDARD SPECIFICATIONS

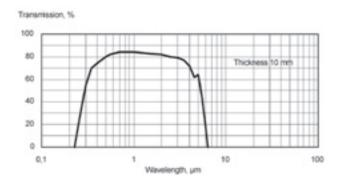
	CRYSTAL GROWTH			
Growth method	Floating zone (FZ)			
Maximum size	Ø 1"			
	CRYSTALLOGRAPHIC PROPERTIES			
Crystal structure	Tetragonal a = 0.459 nm c = 0.296 nm			
Color	Pal			
	PHYSICAL PROPERTIES			
Density	4.26 g.cm ⁻³			
Melting point	1825°C			
Hardness	7 Mohs			
Thermal expansion	Vertical c-axis: $7.2.10^{-6}~\text{K}^{-1}$ Parallel c-axis: $9.19.10^{-6}~\text{K}^{-1}$			
Specific heat capacity	710 J.kg ⁻¹ .K ⁻¹			
Thermal conductivity	12.56 W.m ⁻¹ .K ⁻¹			
Resistivity	7.10 ⁷ Ω.cm			
Dielectric constant	Vertical c-axis: 170 Parallel c-axis: 88			
	OPTICAL PROPERTIES			
Transmission range (thickness 6 mm)	0.43 - 6.0 μm			
Refractive index:	0.6 μm			
n _o	2.61			
n _e	2.90			



YTTRIUM ALUMINIUM GARNET $Y_3AL_5O_{12}$ (YAG) SUBSTRATE

STANDARD SPECIFICATIONS

	C	RYSTAL GROWTH			
Growth method			Czochralski (CZ)		
Maximum size			Ø 2"		
	CRYSTAL	LOGRAPHIC PROPE	RTIES		
Crystal structure		Cu	bic a = 1.2005	nm	
Color			Colorless		
	PHYSICAL PROPERTIES				
Density	4.55 g.cm ⁻³				
Melting point	1940°C				
Hardness	8.5 Mohs				
Thermal expansion	6.9.10 ⁻⁶ K ⁻¹				
Transmission range (thickness 1 mm)	0.3 - 0.5 μm				
Solubility in water	Insoluble				
Solubility in acids	Unessential				
Refractive index n	0.5 µm	1.0 µm	2.0 µm	3.0 µm	4.0 µm
Kenacuve muex n	1.845 1.8197 1.8035 1.7855		1.7602		



YTTRIUM ALUMINATE YAIO₃ (YAP) SUBSTRATE

STANDARD SPECIFICATIONS

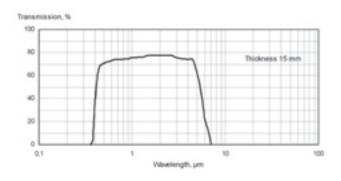
	CRYSTAL GROWTH		
Growth method	Czochralski (CZ)		
Maximum size	Ø 1.5″		
	CRYSTALLOGRAPHIC PROPERTIES		
Crystal structure	Orthorombic a = 0.517 nm b = 0.5307 nm c = 0.7355 nm		
Twin structure	No		
Color	Colorless		
	PHYSICAL PROPERTIES		
Density	4.88 g.cm ⁻³		
Melting point	1870°C		
Thermal expansion	2 - 10.10 ⁻⁶ K ⁻¹		
Dielectric constant	16 - 20		

YTTRIA STABILIZED ZIRCONIA (YSZ) SUBSTRATE

	CRYSTAL GROWTH			
Growth method	Skull melting (ZrO ₂ /Y ₂ O ₃ 92-8% wt)			
Maximum size	Ø 2"			
	CRYSTALLOGRAPHIC PROPERTIES			
Crystal structure	Cubic a = 0.5125 nm			
Color	Colourless			
	PHYSICAL PROPERTIES			
Density	5.92 g.cm ⁻³			
Melting point	2780°C			
Hardness	7.5 - 8 Mohs			
Thermal expansion	8.10 ⁻⁶ K ⁻¹			
Dielectric constant	27			
Thermal conductivity	31.8 W.m ⁻¹ .K ⁻¹			
	CHEMICAL PROPERTIES			
Solubility in water (g/100 cm³)	Not declarate			
Solubility in acids	Not declarate			
Solubility in organic solvents	Not declarate			

	OPTICAL PROPERTIES
Refractive index n	4 μm
	2.24

TRANSMISSION SPECTRUM



ZINC OXIDE ZnO SUBSTRATE

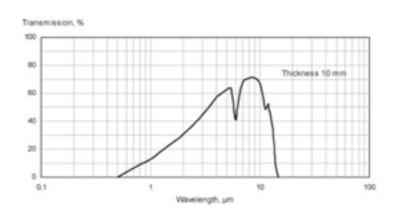
	CRYSTAL GROWTH			
Growth method	Hydrothermal, seeded vapor phase growth			
Maximum size	Ø 35 mm			
	CRYSTALLOGRAPHIC PROPERTIES			
Crystal structure	Hexagonal a = 0.3252 nm c = 0.5213 nm			
	PHYSICAL PROPERTIES			
Density	5.7 g.cm ⁻³			
Melting point	1975℃			
Hardness	4 Mohs			
Thermal expansion	3.16.10 ⁻⁶ K ⁻¹			
Resistivity range	$> 10^2$ - $10^4 \Omega$.cm			
Band gap at 300 K	3.2 eV			
Thermal conductivity	2.5 W.m ⁻¹ .K ⁻¹			
Conductivity type	N-type			
Carrier concentration	10^{10} to 10^{18} cm $^{-3}$			
Dielectric constant	8.5			
	OPTICAL PROPERTIES			
Refractive index n	n _o = 2.026, n _e = 2.041			



ZINC SULFIDE ZnS SUBSTRATE

STANDARD SPECIFICATIONS

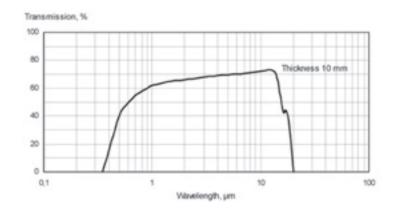
		CRYSTAL GROU	νTΗ			
Growth method	Seeded vapour phase growth					
Maximum size			Ø 40) mm		
	CRYST	ALLOGRAPHIC F	PROPERTIES			
Crystal structure			Cubic a =	0.5411 nm		
	F	HYSICAL PROP	ERTIES			
Density			4.09	g.cm ⁻³		
Melting point			183	30°C		
Hardness			3 M	ohs		
Thermal expansion			7.9.1	0 ⁻⁶ K ⁻¹		
Resistivity range			> 10²-1	.0⁴Ω.cm		
Band Gap (at 300 K)			3.60	5 eV		
Thermal conductivity			1.73 W	/ m ⁻¹ .K ⁻¹		
Conductivity type			N-t	уре		
Carrier concentration			10 ⁵ to 1	.0 ¹⁶ cm ⁻³		
Dielectric constant	9.67					
Dielectric constant			5.	13		
Specific heat capacity	530 J.kg ⁻¹ .K ⁻¹					
	C	HEMICAL PROP	ERTIES			
Solubility in water			Inso	luble		
Solubility in acids	Unessential					
Solubility in organic solvents	Insoluble					
	(OPTICAL PROPE	RTIES			
Absorption coefficient			0.001 cm	¹ at 2.7 μm		
Absorption coefficient	0.2 cm ⁻¹ at 10 μm					
Transmission range (thickness 10 mm)	0.4 - 12.5 μm					
Refractive index n	0.5 µm	0.7 µm	1.0 µm	10.0 µm	11.0 µm	12.0 µm
Retractive index n	2.419	2.332	2.292	2.201	2.186	2.161



ZINC SELENIDE ZnSe SUBSTRATE

STANDARD SPECIFICATIONS

		CRYSTAL GR	OWTH			
Growth method		Seeded vapour phase growth				
Maximum size			Ø	40 mm		
	CRYS	TALLOGRAPHI	C PROPERTIES			
Crystal structure		Cubic a = 0.5668 nm				
Cleavage				<110>		
		PHYSICAL PRO	PERTIES			
Density			5.2	26 g.cm ⁻³		
Melting point			1	L520°C		
Hardness			4	4 Mohs		
Thermal expansion			7.6	5.10 ⁻⁶ K ⁻¹		
Thermal conductivity			12.9	7 W.m ⁻¹ .K ⁻¹		
Specific heat capacity			35	5 J.kg ⁻¹ .K ⁻¹		
Resistivity range			> 1	10 ⁸ Ω.cm		
Band Gap (at 300 K)		3.66 eV				
Conductivity type			I	N-type		
Carrier concentration			10 ⁵ t	to 10 ¹⁷ cm ⁻³		
		CHEMICAL PRO	PERTIES			
Solubility in water			Ir	nsoluble		
Solubility in acids	Soluble					
Solubility in organic solvents	Insoluble					
		OPTICAL PROI	PERTIES			
Absorption coefficient	0.005 cm ⁻¹ at 10.6 μm					
Transmission range (thickness 10mm)	0.55 - 18.0 μm					
Refractive index n	1.0 µm	3.0 µm	5.0 µm	10.0 µm	12.0 µm	15.0 µm
Reflactive illuex II	2.4894	2.4376	2.4296	2.4067	2.3936	2.3662





ZINC TELLURIDE ZnTe SUBSTRATE

	CRYSTAL GROWTH			
Growth method	Seeded vapour phase growth			
Maximum size	Ø 40 mm			
	CRYSTALLOGRAPHIC PROPERTIES			
Crystal structure	Cubic a = 0.6089 nm			
	PHYSICAL PROPERTIES			
Density	5.636 g.cm ^{⋅3}			
Melting point	1290℃			
Hardness	4 Mohs			
Thermal expansion	8.36.10 ⁻⁶ K ⁻¹			
Resistivity range	> 10 ⁵ Ω.cm			
Band gap (at 300 K)	2.28 eV			
Thermal conductivity	12.39 W.m ⁻¹ .K ⁻¹			
Conductivity type	P-type			
Carrier concentration	10^{10} to 10^{17} cm ⁻³			
Dielectric constant	8.1			
Dielectric Constant	7.28			
	OPTICAL PROPERTIES			
Refractive index n	2.68			

Glass & Fused Quartz Substrates

BOROSILICATE GLASS

Borosilicate glass, known under trade names such as Pyrex® and Duran®, is widely used in chemical and engineering applications.

This glass is chemically resistant, has a low thermal expansion coefficient and can be used at relatively high temperatures. Our high quality borosilicate glass substrates are optically polished on both surfaces. The excellent

flatness and a low warp of our borosilicate wafers and the thermal coefficient of expansion close to the one of silicon, facilitate sophisticated applications in the semiconductor industry such as anodic bonding to silicon and various micro optical applications.

On request, our borosilicate glass wafers can be made with a ground SEMI standard flat or a notch.

APPLICATIONS

- Semiconductor applications
- Micro lithography
- Substrates for anodic bonding
- Optical substrates

- Micro system technology
- Micro mechanics
- Microstructure applications

GENERAL PROPERTIES		
Density 2.23 g.cm ⁻³		
MECHANICAL PROPERTIES		
Young's modulus 64 GPa		
Hardness (Knoop test)	480	

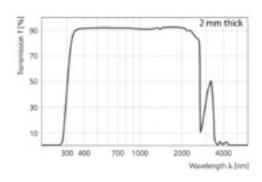


	THERMAL PROPERTIES		
Max. use temperature 500°C			
Thermal conductivity	1.14 W.m ⁻¹ .K ⁻¹		
Coefficient of linear expansion	3.3.10 ⁻⁶ K ⁻¹		
	ELECTRICAL PROPERTIES		
Volume resistance	10¹⁵ Ω.cm		
Dielectric constant	4.6 (20°C, 1 MHz)		
Dielectric strength	30 kV.mm ⁻¹		
	OPTICAL PROPERTIES		
Refractive index n	1.474 at 588 nm		

AVAILABLE THICKNESS

THICKNESS (mm)	TOLERANCE (mm)
0.7	+/- 0.07
1.1	+/- 0.1
1.75	+/- 0.2
2	+/- 0.2
2.25	+/- 0.2
2.75	+/- 0.2
3.3	+/- 0.2
3.8	+/- 0.2
5	+/- 0.2
6.5	+/- 0.2
7.5	+/- 0.3
9	+/- 0.3
11	+/- 0.3
13	+/- 0.3
15	+/- 0.3
17	+/- 0.5
19	+/- 0.5
21	+/- 0.7
25.4	+/- 1.0

Other thickness are available on request.



QUARTZ/SILICA SUBSTRATE

Quartz glass is an extremely versatile material used in a range of different applications. It has outstanding thermal properties, excellent optical transmission, with good electrical and corrosion performance.

There are two basic ways of making quartz / silica glass:

- By melting silica grains either by gas or electrical heating (the type of heating affects some optical properties). This material can be transparent or, for some applications, opaque.
- By synthesising the glass from chemicals.

This synthetic material, normally referred to as synthetic fused silica, has better optical properties and is somewhat more expensive than the other type.

ADVANTAGES

- Incredibly thermally shock resistant (can be taken from red heat and plunged into water without cracking)
- Low coefficient of thermal expansion
- Optical transmission properties from ultra violet to infra red
- Good chemical resistance
- Excellent electrical insulator

APPLICATIONS

- Windows
- Lenses
- Mirror substrates
- Crucibles, trays and boats
- UV transmitting optics (synthetic fused silica)
- IR transmitting optics
- Metrology components

DIFFERENCES BETWEEN FUSED SILICA AND QUARTZ WAFER

Very often terms such as quartz, silica, fused quartz and fused silica tend to be used interchangeably.

FUSED SILICA WAFER (SYNTHETIC SILICA)	FUSED QUARTZ WAFER (NATURAL SILICA)
• High OH content >1200	• Low OH content > 150
Excellent optical properties	 Excellent thermal properties
Higher transmission in the UV range	• Contain some bubbles, inclusions and contaminants
Free bubbles, inclusions and contaminants	High fluorescence
Very low fluorescence	• Impurity 20 - 40 ppm
Impurity 5 ppm	

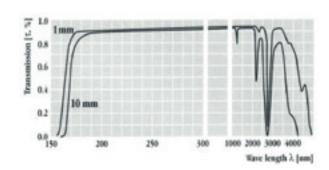


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STANDARD SPECIFICATIONS

GENERAL PROPERTIES				
Density	Density 2.2 g.cm ⁻³			
	MECHANICAL PROPERTIES			
Young's modulus	72 Gpa			
Design tensile strength	48 Mpa			
Design compressive strength	1100 Mpa			
	THERMAL PROPERTIES			
Max. Use temperature	950 - 1300℃			
Thermal conductivity	1.4 W.m ⁻¹ .K ⁻¹			
Coefficient of linear expansion	0.55.10 ⁻⁶ K ⁻¹			
	ELECTRICAL PROPERTIES			
Volume resistance	1016 Ω.cm			
Dielectric constant	3.7 (20°C, 1 MHz)			
Dielectric strength	40 kV.mm ⁻¹			

TRANSMISSION SPECTRUM



OPTICAL TRANSMISSION

WAVELENGTH (nm)	FUSED SILICA (SYNTHETIC SILICA)	FUSED QUARTZ (NATURAL SILICA)
190	86.42	73.84
200	86.88	75.16
210	88.51	79.90
220	89.09	85.69
230	89.58	87.57
240	89.90	87.58
250	90.12	88.64
260	90.46	90.11
280	90.89	90.82
300	91.14	91.15
350	91.49	91.45
400	91.72	91.75
500	92.08	91.99
750	92.26	92.32
1000	92.52	92.48
2000	93.25	93.48
2500	91.58	93.56

Ceramic Substrates

ALUMINA Al₂O₃ SUBSTRATE (MICROPOLISHED)

Pure alumina ceramics due to their high insulation resistance at elevated temperatures, high dielectric strength, low dielectric loss tangent at high frequencies is one of the best dielectric materials available for use in applications requiring electrical insulation.

The mechanical strength of pure alumina ceramics may be extremely high if properly controlled by the size and homogeneity of the constituent crystallites. It is recommended to use ceramics in compression because compressive strength is nearly 10 times that of the flexural strength. This may be achieved through design or by the establishment of operating conditions.

Thermal and chemical properties of pure alumina ceramics are always of great interest. Thermal conductivity is nearly equivalent to stainless steel. Pure alumina ceramics is inert to oxidation, not corroded by chemical agents and not subjected to radiation damage.

APPLICATIONS

- Mechanical seal faces
- · Nozzles for abrasives spraying corrosive reagents
- High pressure liquid media

- Laboratory apparatus components
- Metalized parts of high vacuum and high-voltage feed-through, and many other applications

Purity	96%
Color	White
Density	3.72 g.cm ⁻³
Thermal expansion	8.10 ⁻⁶ °C ⁻¹
Loss tangent	4.10 ⁻⁴ at 1 MHz

Thermal conductivity	24 W.m ⁻¹ .K ⁻¹	
Dielectric constant (at 1 MHz)	9.8	
Volume resistivity (Ω.m)	> 10 ¹³ at 20°C > 3.10 ⁷ at 500°C	
Flexural strength	350 N.mm ⁻²	



Glassy Carbon Substrates

Glassy carbon, also called vitreous carbon, is an advanced material of pure carbon combining glassy and ceramic properties with these of graphite. Unlike graphite, glassy carbon has a fullerene-related microstructure. This leads to a great variety of unique material properties.

SPECIAL PROPERTIES

- High temperature resistance in inert gas or vacuum up to 3000°C
- High purity
- Extreme corrosion resistance
- Impermeability to gas and liquids, no open porosity
- No wetting by melts
- High hardness and strength

- Low density
- High surface quality, no particle generation
- Low thermal expansion
- Extreme resistance to thermal shock
- Isotropy of physical and chemical properties
- Good electrical conductivity
- Biocompatibility

	PLATES	PLATES / FILMS
Maximum service temperature (vacuum or inert gas)	3000°C	1000°C
Density	1.42 g.cm ⁻³	1.54 g.cm ⁻³
Open porosity	0%	0%
Permeability coefficient	10 ⁻⁹ cm ² .s ⁻¹	10 ⁻¹¹ cm ² .s ⁻¹
Vickers hardness	230 HV1	340 HV1
Flexural strength (4 point)	260 N.mm ⁻²	210 N.mm ⁻²
Young's modulus	35 kN.mm ⁻²	35 kN.mm ⁻²
Compressive strength	480 N.mm ⁻²	580 N.mm ⁻²
Specific electrical resistance (RT)	45 Ω.μm	50 Ω.μm
Thermal conductivity (RT)	6.3 J.K ⁻¹ .m ⁻¹ .s ⁻¹	4.6 J.K ⁻¹ .m ⁻¹ .s ⁻¹
Median linear coefficient of expansion (20-200°C)	2.6.10 ⁻⁶ K ⁻¹	3.5.10 ⁻⁶ K ⁻¹

AVAILABLE DIMENSIONS

	THICKNESS	DIMENSIONS
PLATES	0.3 mm 0.5 mm	25 x 25 mm 50 x 50 mm 100 x 100 mm
	1 to 6 mm	25 x 25 mm 50 x 50 mm 100 x 100 mm 200 x 200 mm
FILMS	60 μm 100 μm 140 μm 180 μm	25 x 25 mm 50 x 50 mm 100 x 100 mm

Other dimensions and custom made parts are available on request.





HOPG & Mica Substrates

HIGHLY ORDERED PYROLYTIC GRAPHITE HOPG

HOPG, is a relatively new form of high purity carbon and provides microscopists with a renewable and smooth surface. Unlike mica, HOPG is completely non-polar, and for samples where elemental analysis will also be done, it provides a background with only carbon in the elemental signature. The extreme smoothness of HOPG gives results in a featureless background, except at atomic levels of resolution.

The structure is strictly columnar, that is, the columns run vertically within the flat slab of the material. The grain boundaries can be seen on the lateral surfaces. The mosaic spread is the angle of deviation of the grain's boundary from this perpendicular axis (of the columnar structure).

USE AT ELEVATED TEMPERATURES

As more and more applications are found for HOPG in research and technology, more and more applications are requiring good high temperature characteristics. We can report the following information which should be useful for those contemplating such usage:

- Air: 500°C (Starts to burn)
- Vacuum at 0.1 Torr: 2500°C
- Inert atmosphere (N₂, Ar, He): 3500°C

DENSITY OF HOPG

The density for all three grades (SPI-1, SPI-2, and SPI-3) is 2.27 g.cm⁻³.

GRADE SPI-1

Comparable to the very best "calibration grade" HOPG and exhibiting a 0.4° +/- 0.1° . This is the most highly ordered, lateral grain size is typically up to about 3 mm but can be as large as 10 mm, and is used primarily for instrument calibration purposes or for research experiments where for some reason, the very ultimate in HOPG order is needed.

GRADE SPI-2

This grade exhibits a mosaic angle as small as 0.8° +/- 0.2° . This grade is slightly less highly ordered than SPI-1 but is acceptable for most users. The lateral grain size can be up to 0.5 mm but can be as large as 1 mm.

GRADE SPI-3

Exhibits a mosaic angle as small as 3.5° +/- 1.5°. This grade is much less highly ordered and has a grain size not larger than the range of 30-40 nm.

SQUARES & RECTANGLES

DIMENSIONS (mm)	P/N SPI-1 GRADE	P/N SPI-2 GRADE	P/N SPI-3 GRADE
5 x 5 x 1	476HP-AB	479HP-AB	490HP-AB
7 x 7 x 1	498HP-AB	480HP-AB	491HP-AB
10 x 10 x 1	439HP-AB	436HP-AB	429HP-AB
10 x 10 x 2	438HP-AB	446HP-AB	440HP-AB
12 x 12 x 1	426HP-AB	-	-
10 x 10 x 0.2	424HP-AB	-	-
10 x 10 x 3	-	456HP-AB	443HP-AB
20 x 20 x 1	-	466HP-AB	449HP-AB
20 x 20 x 2	-	444HP-AB	448HP-AB
20 x 20 x 3	-	447HP-AB	451HP-AB

DISCS

3 mm diameter to fit into a standard TEM grid holder, 50-75 µm thick, shipped in a BEEM Dial-A-Grid box.

Packaging	P/N
Pack of 20 discs	423HP-CA
Pack of 100 discs	423HP-MB

MICA SHEETS, STRIPS AND DISCS

The only mica offered by Neyco is of the muscovite type and indeed, we offer only the highest qualities of the mineral.

APPLICATIONS

For AFM studies, and for those making either carbon films or doing thin film coating research and wanting a higher quality mica as defined as having fewer "steps" on a freshly cleaved surface, we would recommend grade V-4. This grade is also great for use with AFM where a polar substrate is desired or

where polarity of the substrate just does not matter.

For AFM calibration studies or perhaps the ultimate substrate for carbon film production, we offer the grade V-1. Mica can also be used as a substrate for binding cells to be characterized by TEM.

- Chemical Formula: K₂OAl₂O₃SiO₂
- Appearance: Semi clear to gray translucent sheets, strips, and discs
- Specific Gravity: 2.7 g.cm⁻³
- Hardness on Mohs scale of hardness: 2 2.25



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- Grade V-1 Muscovite: Highest possible quality
- Grade V-4 Muscovite: Premium research quality
- Grade V-5 Muscovite: Research quality

SQUARES & RECTANGLES

THICKNESS	LATERAL SIZE (mm)	PACKAGING	GRADE V-1	GRADE V-4	GRADE V-5
	50 x 25	Pkg of 1	01792-AB	-	-
	50 x 25	Pkg of 20	01792-CA	01876-CA	-
	50 x 25	Pkg of 100	01792-MB	01876-MB	-
	25 x 25	Pkg of 1	01872-AB	-	-
	25 x 25	Pkg of 20	01872-CA	-	-
0.15 mm	25 x 25	Pkg of 100	01872-MB	-	-
0.13	15 x 15	Pkg of 20	01868-CA	01869-CA	-
	15 x 15	Pkg of 100	01868-MB	01869-MB	-
	75 x 50	Pkg of 20	-	-	01804-CA
	75 x 25	Pkg of 20	-	-	01805-CA
	75 x 25	Pkg of 100	-	-	01805-MB
	40 x 10	Pkg of 100	-	-	01806-MB
	25 x 25	Pkg of 20	-	01870-CA	-
	25 x 25	Pkg of 100	-	01870-MB	-
	50 x 25	Pkg of 20	-	01791-CA	-
	50 x 25	Pkg of 100	-	01791-MB	-
0.26 mm	75 x 25	Pkg of 20	-	01875-CA	-
	75 x 25	Pkg of 100	-	01875-MB	-
	80 x 40	Pkg of 25	-	01918-CF	-
	40 x 10	Pkg of 10	-	-	01806A-BA
	40 x 10	Pkg of 100	-	-	01806A-MB

DISCS

THICKNESS	DIAMETER (mm)	PACKAGING	GRADE V-1	GRADE V-4	GRADE V-5
0.05	3.05	Pkg of 100	01900-MB	-	-
0.05 mm	3.05	Pkg of 20	01900-CA	-	-
	9.5	Pkg of 100	01873-MB	01874-MB	-
	9.5	Pkg of 20	01873-CA	01874-CA	-
0.15 mm	12	Pkg of 100	01877-MB	01879-MB	-
	15	Pkg of 100	01878-MB	01880-MB	-
	22	Pkg of 100	01920-MB	01921-MB	-
0.26 mm	9.9	Pkg of 20	-	-	01871-CA
0.26 mm	9.9	Pkg of 100	-	-	01871-MB
0.275 to 0.325 mm	12	Pkg of 100	01925-MB	-	-
	25	Pkg of 100	01926-MB	-	-
0.05 mm	3.05	Pkg of 100	-	01923-MB	-
	3.05	Pkg of 20	-	01923-CA	-

Thin Film Deposition

THIN FILM DEPOSITION ON REQUEST

Neyco offers thin films deposition on request on the various substrates such as: Platinum, Gold, ITO, Titanium, Chromium.



 See Silicon Wafers in this section about Thermal Oxidation of Si wafers

ITO-COATINGS ON GLASS SUBSTRATE

Whenever an electrically conductive surface that at the same time offers a high optical transparency is required, ITO-coating glass series are used. ITO-coating glass is achieved by sputter-coating a thin conductive layer of indium-tin-oxide onto high quality glass substrates.

Because of the low electrical sheet resistances we have available, our ITO-coatings have often be used to shield electromagnetic fields while still transmitting most of the visible light.

Our series of conductive transparent oxide coatings feature a SiO_2 passivation layer. This quartz barrier layer is only a few nanometers thick, and is located between the substrate and the ITO-coating. This offers an increased electrical insulation performance and minimizes possible leaching of alkali-oxides from the glass into liquid crystals. The process of coating this SiO_2 passivation layer between the ITO thin film coating and the glass substrate, is advantageous for most electronic applications and is efficiently integrated into the production process.



APPLICATIONS

- Display technology
- Transparent ITO electrode
- ITO coated microscope slide
- Circuit substrate
- Micro structuring application
- Transparent EMF/EMI/EMC/RFI/HF shielding glass
- Flat antennas for mobile communication
- Conducting glass
- De-Icing applications
- Heatable ITO slide & cover slip

SPECIAL PROPERTIES

- Electrically conductive and optically transparent
- · High VIS-NIR light transmission
- · High quality glass substrate
- SiO₂ barrier layer
- Low roughness
- · High sheet resistance homogeneity
- · Uniform transmission homogeneity
- Reflecting in the infrared range

REFRACTIVE INDEX

We present the refractive index data for the ITO coating. It is the refractive index value used for calculating our ITO film performances. Remember that the ITO coatings made are sputtered and therefore are denser than coatings made by vacuum evaporation.

WAVELENGTH (nm)	REFRACTIVE INDEX	EXTINCTION COEFFICIENT
400	2.15	0.025
425	2.1	0.018
450	2	0.01
506	2	0.0087
600	2	0.0065
650	2	0.0044
700	2	0.0042
750	2	0.0042
800	2	0.004
1065	2	0.004

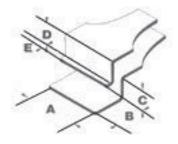
RESISTIVITY RANGE

Resistivity range: 10-15, 15-30, 30-60, 70-100 Ω .cm according ITO thickness.

Wafer Tweezers

We offer 18 different tweezers styles, mostly from the SPI-Swiss collection.





STYLE	DIMENSIONS (in mm)					
SITCE	Α	В	C	D	E	
Style #2W	6.5	5	2.5	4	-	
Style 2WF	6.5	9	2.5	4	2.5	
Style 2WFG	6.5	9	2.5	4	2.5	
Style 3W	9.5	10	2.5	4	-	
Style 3WF	9.5	10	2.5	4	2.5	
Style 3WFG	9.5	10	2.5	4	2.5	
Style 4W	12	9	2.5	4	-	
Style 4WF	12	9	2.5	4	2.5	
Style 4WFG	12	9	2.5	4	2.5	

	STYLE	DESCRIPTION	P/N
	Style #2W Length: 120 mm	Antimagnetic Stainless Steel	0S2W0-XD
		PTFE Coated Antimagnetic Stainless Steel	S2W0T-XD
	Style 2WF Length: 119 mm	Antimagnetic Stainless Steel	0S2WF-XD
		PTFE Coated Antimagnetic Stainless Steel	S2WFT-XD
Style 2WFG	Style 2WFG	Antimagnetic Stainless Steel	S2WFG-XD
	Length: 120 mm	PTFE Coated Antimagnetic Stainless Steel	S2WFGT-XD
	Style 3W	Antimagnetic Stainless Steel	0S3W0-XD
	Length: 125 mm	PTFE Coated Antimagnetic Stainless Steel	S3W0T-XD
	Style 3WF	Antimagnetic Stainless Steel	0S3WF-XD
	Length: 125 mm	PTFE Coated Antimagnetic Stainless Steel	S3WFT-XD
	Style 3WFG Length: 125 mm	Antimagnetic Stainless Steel	S3WFG-XD
		PTFE Coated Antimagnetic Stainless Steel	S3WFGT-XD
	Style 4W Length: 133 mm	Antimagnetic Stainless Steel	0S04W-XD
		PTFE Coated Antimagnetic Stainless Steel	S04WT-XD
	Style 4WF Length: 133 mm	Antimagnetic Stainless Steel	0S4WF-XD
		PTFE Coated Antimagnetic Stainless Steel	S4WFT-XD
	Style 4WFG Length: 125 mm	Antimagnetic Stainless Steel	S4WFG-XD
		PTFE Coated Antimagnetic Stainless Steel	S4WFGT-XD
Style 33A Length: 112 mm Width at end: 6.5 mm	Antimagnetic Stainless Steel	OS33A-XD	
		PTFE Coated Antimagnetic Stainless Steel	S33AT-XD
	Style 34A Length: 127 mm Width at end: 6.2 mm	Antimagnetic Stainless Steel	0S34A-XD
		PTFE Coated Antimagnetic Stainless Steel	S34AT-XD

	STYLE	DESCRIPTION	P/N
	Style 35A Length: 121 mm Width at end: 6.5 mm	Antimagnetic Stainless Steel	0S35A-XD
		PTFE Coated Antimagnetic Stainless Steel	S35AT-XD
	Style 36A Length: 124 mm Width at end: 6.2 mm	Antimagnetic Stainless Steel	0S36A-XD
		PTFE Coated Antimagnetic Stainless Steel	S36AT-XD
	Style 37S Length: 124 mm Width at end: 6.5 mm	Antimagnetic Stainless Steel	0S37S-XD
		PTFE Coated Antimagnetic Stainless Steel	S37ST-XD
7	Style 84A Length (Total): 121 mm Width of pick up: 2 mm Length of top pick up: Top: 5 mm Bottom: 6 mm	Antimagnetic Stainless Steel	0S84A-XD
		PTFE Coated Antimagnetic Stainless Steel	S84AT-XD
	Style 85C Length: 121 mm Width at end: 7.0 mm	Antimagnetic Stainless Steel	0S85C-XD
		PTFE Coated Antimagnetic Stainless Steel	S85CT-XD
	Style 86B Length: 121 mm Width at end: 2.7 mm	Antimagnetic Stainless Steel	0S86B-XD

See Section L - Sample Preparation in this catalogue for other tweezers.